



Attorney Docket No. 740756-2681
Application No. 10/728,987
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)
Akiharu MIYANAGA et al.) Group Art Unit: 1762
Serial No. 10/728,987)
Filed: December 8, 2003) Examiner: W. Markham
For: PULSED PLASMA CVD METHOD)
FOR FORMING A FILM) Confirmation No.: 1100
(as amended))

AMENDMENT

U.S. Patent & Trademark Office
2011 South Clark Place
Customer Window, Mail Stop Amendment
Crystal Plaza Two, Lobby, Room 1B03
Arlington, VA 22202

Sir:

The following is presented in response to the non-final Office Action mailed April 12, 2004, in connection with the above-captioned patent application.